



Prof. Dr.-Ing. habil. Eberhard Manske

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Biography

Eberhard Manske received his diploma in electrical engineering from the Technical University of Ilmenau in 1982. He obtained his doctorate in 1986 and habilitated in 2006 in the field of precision metrology. Since 2008, he has held a professorship for "Production and Precision Metrology" at the Technical University of Ilmenau.

From 2008 to 2013, he was spokesperson for the Collaborative Research Centre "Nanopositioning and Nanomeasuring Machines (SFB 622)" and from 2017-2020 he headed the Research Training Group "Advanced and laser-based 3D nanofabrication in extended macroscopic working areas (NanoFab)" funded by the German Research Foundation.

His research activities focus on the development of nanopositioning and nanomeasuring machines, particularly in the fields of high-precision laser interferometry, laser stabilisation, frequency comb technology, optical and tactile nanosensors and scanning probe methods.

Together with Dr Denis Dontsov (SIOS Meßtechnik GmbH), he established World Interferometry Day in 1921, which is celebrated annually at the beginning of April to mark the first successful interferometer experiment by Albert Michelson in 1881.